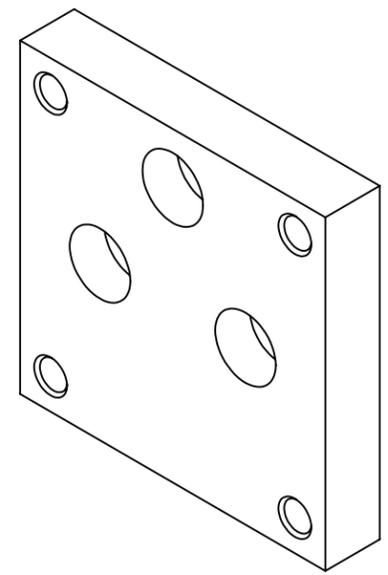


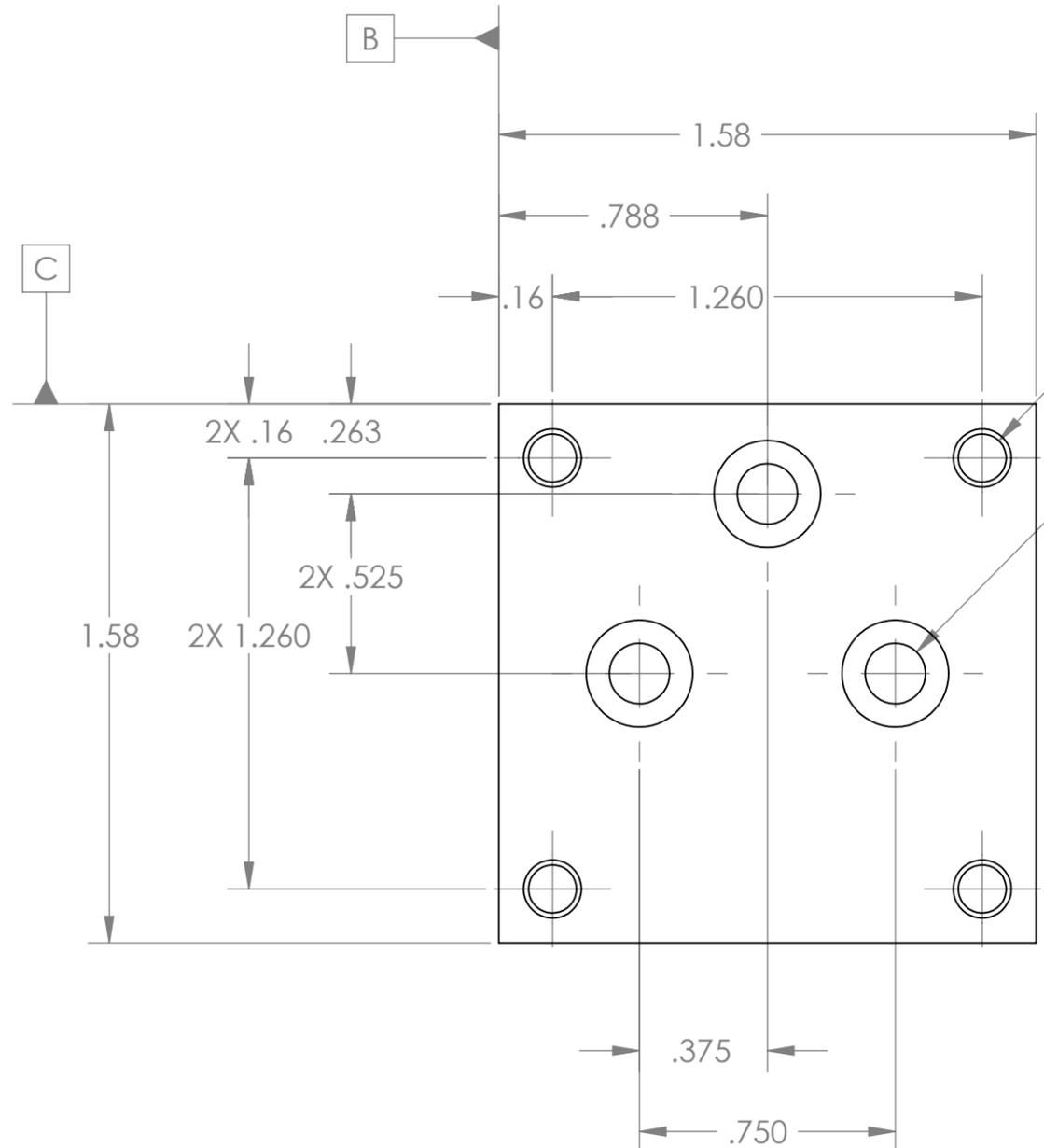
8 7 6 5 4 3 2 1

NOTES CONTINUED:
 5. SCRIBE, ENGRAVE, OR MECHANICALLY STAMP (NO INKS OR DYES) DRAWING PART NUMBER, REVISION (AND VARIANT OR "TYPE" IF APPLICABLE) ON NOTED SURFACE OF PART FOLLOWED ON THE NEXT LINE WITH A THREE DIGIT SERIAL NUMBER. SERIAL NUMBERS START AT 001 FOR THE FIRST ARTICLE AND PROCEED CONSECUTIVELY. USE MINIMUM 0.12" HIGH CHARACTERS, UNLESS THE SIZE OF THE PART DICTATES SMALLER CHARACTERS. A VIBRATORY TOOL MAY BE USED.
 EXAMPLE: DXXXXXX-VY, TYPE-XX, S/N XXX

REV.	DATE	DCN #	DRAWING TREE #
v1	22 AUG 2010	E100182-v1	-
-	-	-	-
-	-	-	-

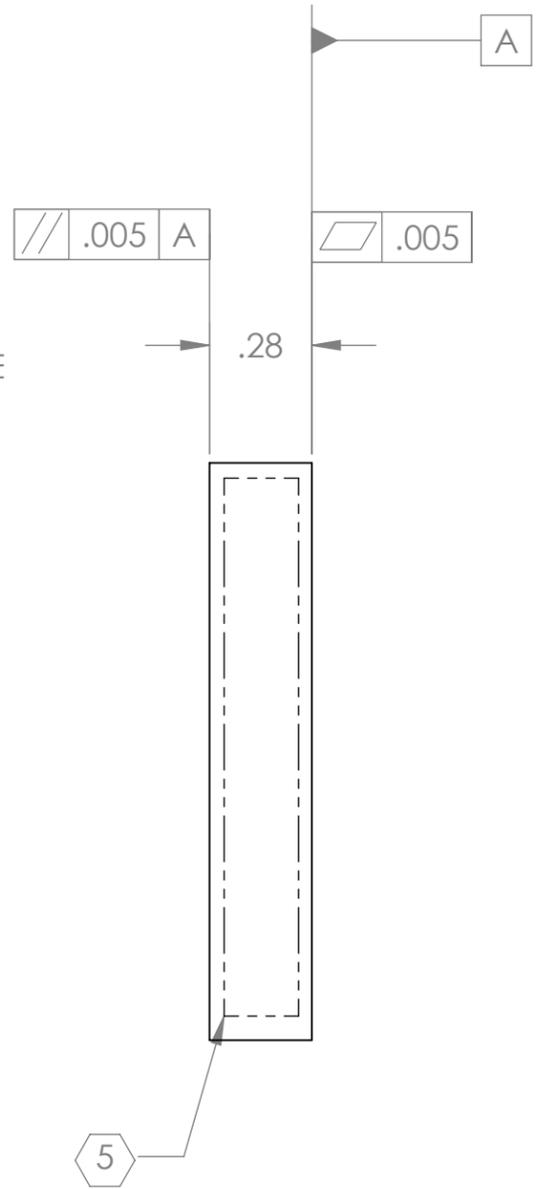


ISO VIEW



4X ϕ .141 THRU
 \surd ϕ .170 X 90°, NEAR SIDE

3X ϕ .177 THRU
 \sqsubset ϕ .313 ∇ .179



- 8. MACHINE ALL SURFACES TO REMOVE OXIDES AND MILL FINISH, USE OF ABRASIVE TECHNIQUES IS NOT ALLOWED.
- 7. DO NOT USE SANDPAPER, SCOTCH BRITE OR SIMILAR PRODUCTS.
- 6. ALL PART SHALL BE MANUFACTURED IN ACCORDANCE WITH LIGO SPECIFICATION E0900364.

NOTES AND TOLERANCES: (UNLESS OTHERWISE SPECIFIED)	
DIMENSIONS ARE IN INCHES	
TOLERANCES: .XX \pm .01 .XXX \pm .005 ANGULAR \pm 1.0°	
1. INTERPRET DRAWING PER ASME Y14.5-1994.	2. REMOVE ALL SHARP EDGES, R.02 MIN.
3. DO NOT SCALE FROM DRAWING.	4. ALL MACHINING FLUIDS MUST BE FULLY SYNTHETIC, FULLY WATER SOLUBLE AND FREE OF SULFUR, SILICONE, AND CHLORINE.
MATERIAL	FINISH
6061-T6 Al	N/A μ inch

CALIFORNIA INSTITUTE OF TECHNOLOGY MASSACHUSETTS INSTITUTE OF TECHNOLOGY		PART NAME		ALIGO AOS OPLEV TELESCOPE MOUNT BASE	
SYSTEM	ADVANCED LIGO	SUB-SYSTEM	AOS	DESIGNER	C. CONLEY 25 JUN 2010
DRAFTER	N. KILPATRICK 22 AUG 2010	CHECKER		APPROVAL	
SIZE	B	DWG. NO.	D1001646	REV.	v1
SCALE:	2:1	PROJECTION:		SHEET 1 OF 1	

D1001646 ALIGO AOS Oplev Telescope Mount Base, PART PDM REV: X-006, DRAWING PDM REV: X-005

8 7 6 5 4 3 2 1